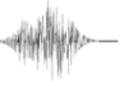




UNIVERSITÀ DEGLI STUDI  
DI PERUGIA

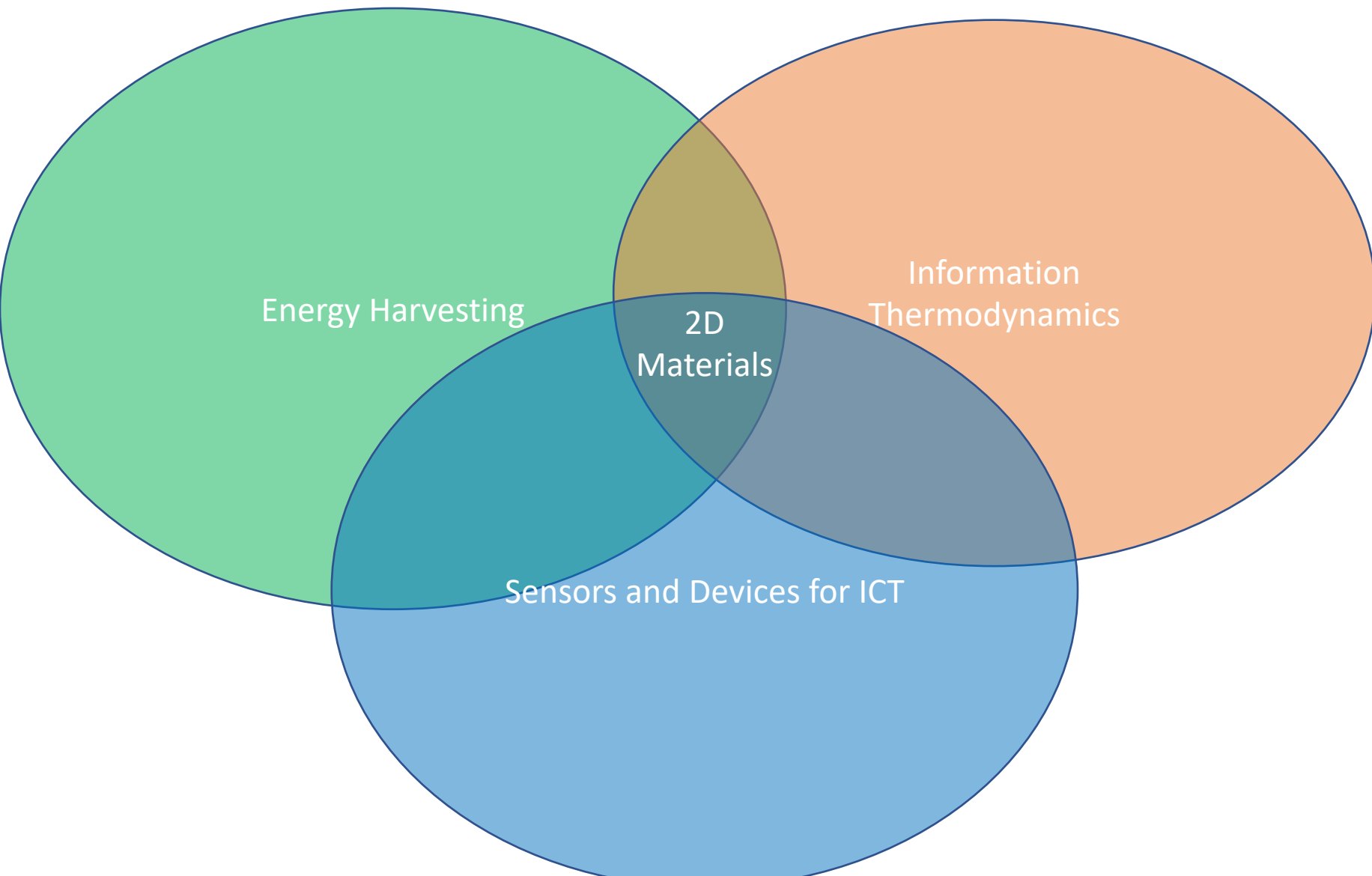
**NiPS** Laboratory  
Noise in Physical Systems



# Studio delle proprietà elettroniche ed ottiche di materiali bidimensionali

Igor Neri

# Research Activities

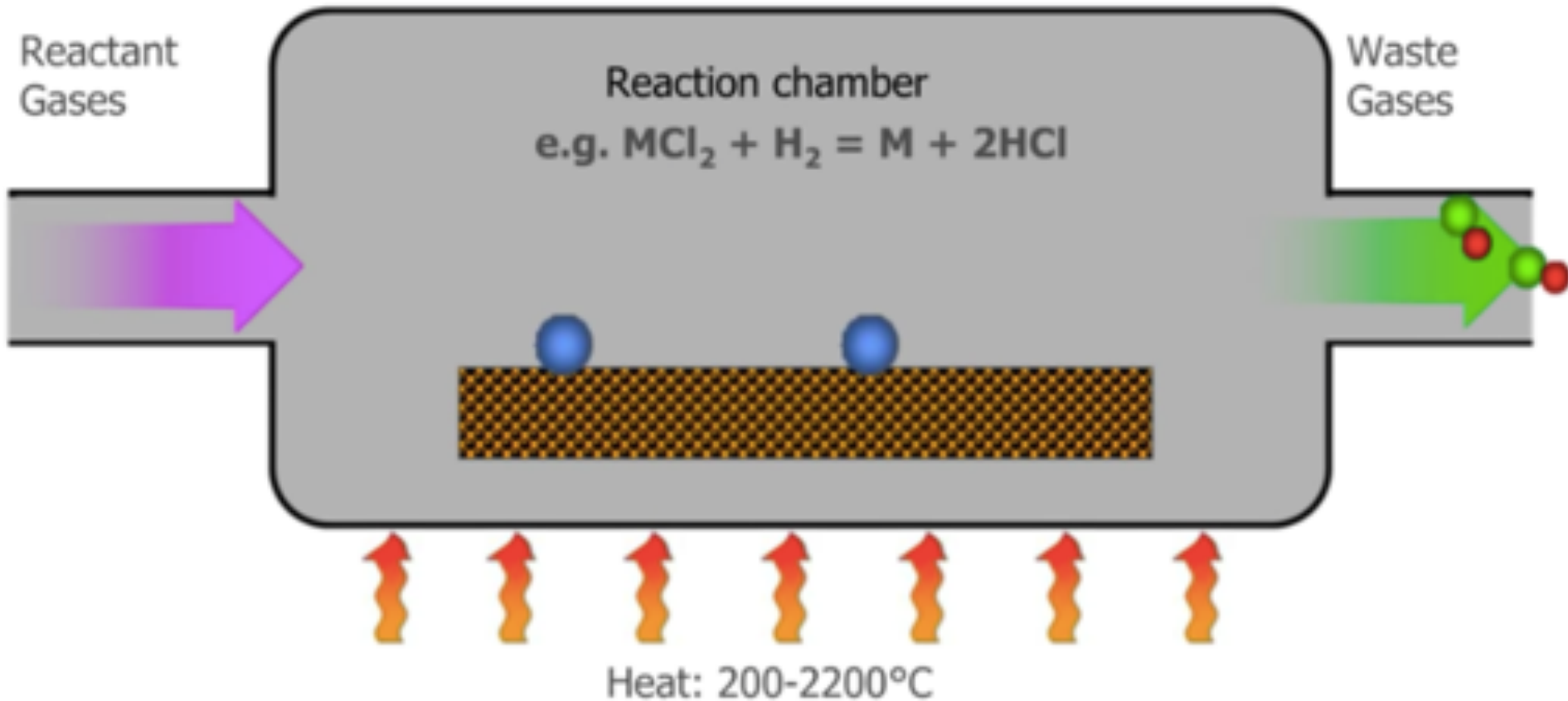


# Outline

- Preparation techniques
- Thickness measurements
- Electronic properties
- Fast thickness identification
- Applications
  - Strain sensors
  - NEMS memories
  - Heat rectifier

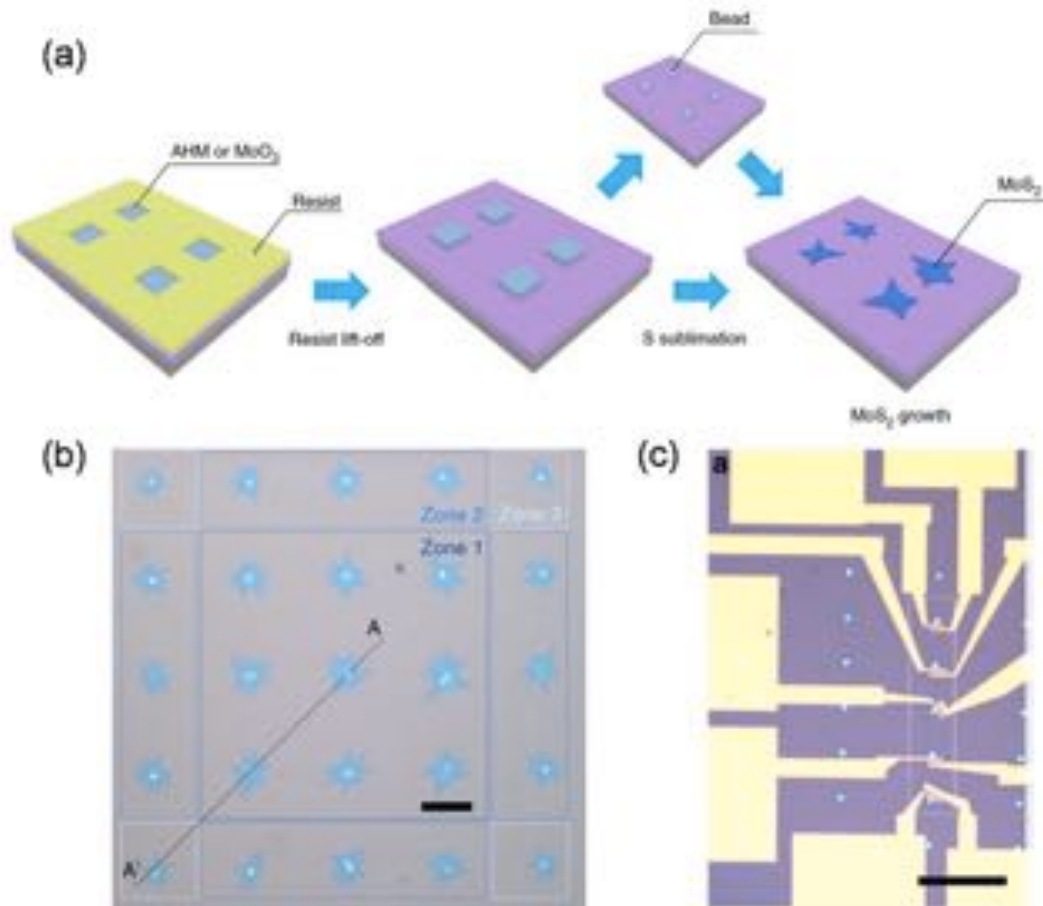
# Preparation techniques

## 1) Chemical Vapor Deposition



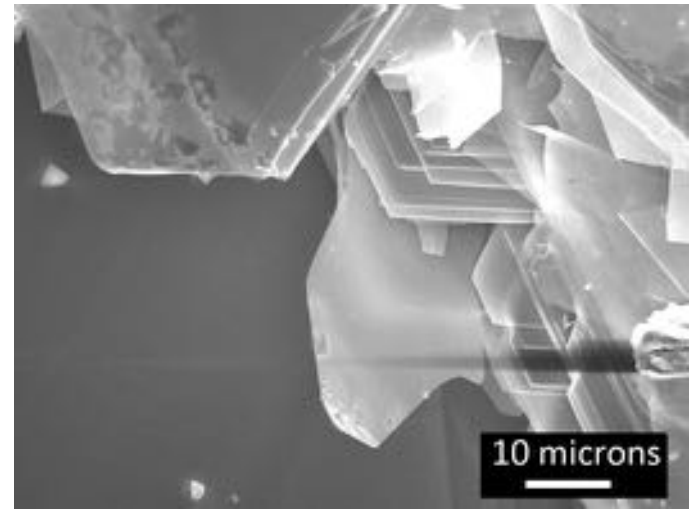
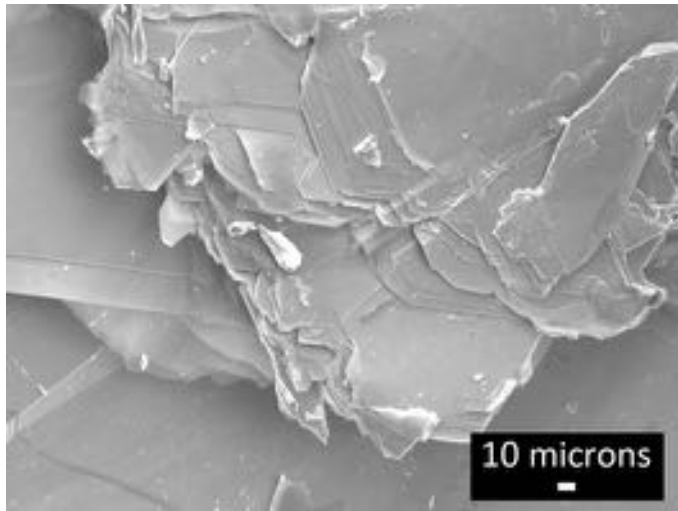
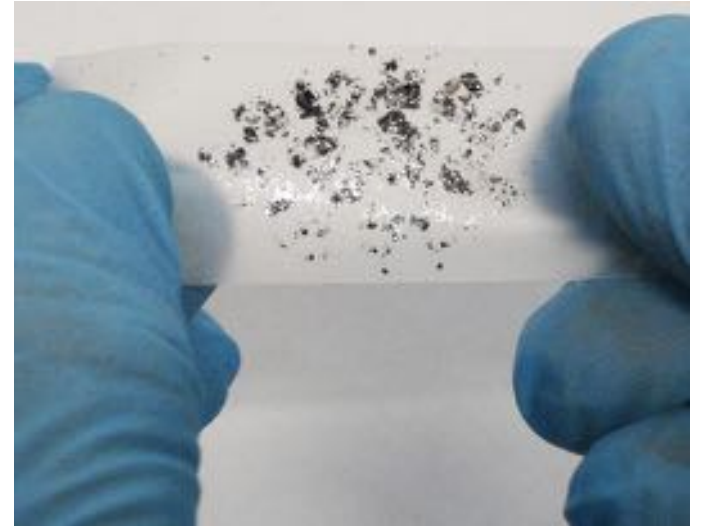
# Preparation techniques

## 2) Metal-Guided Selective Growth

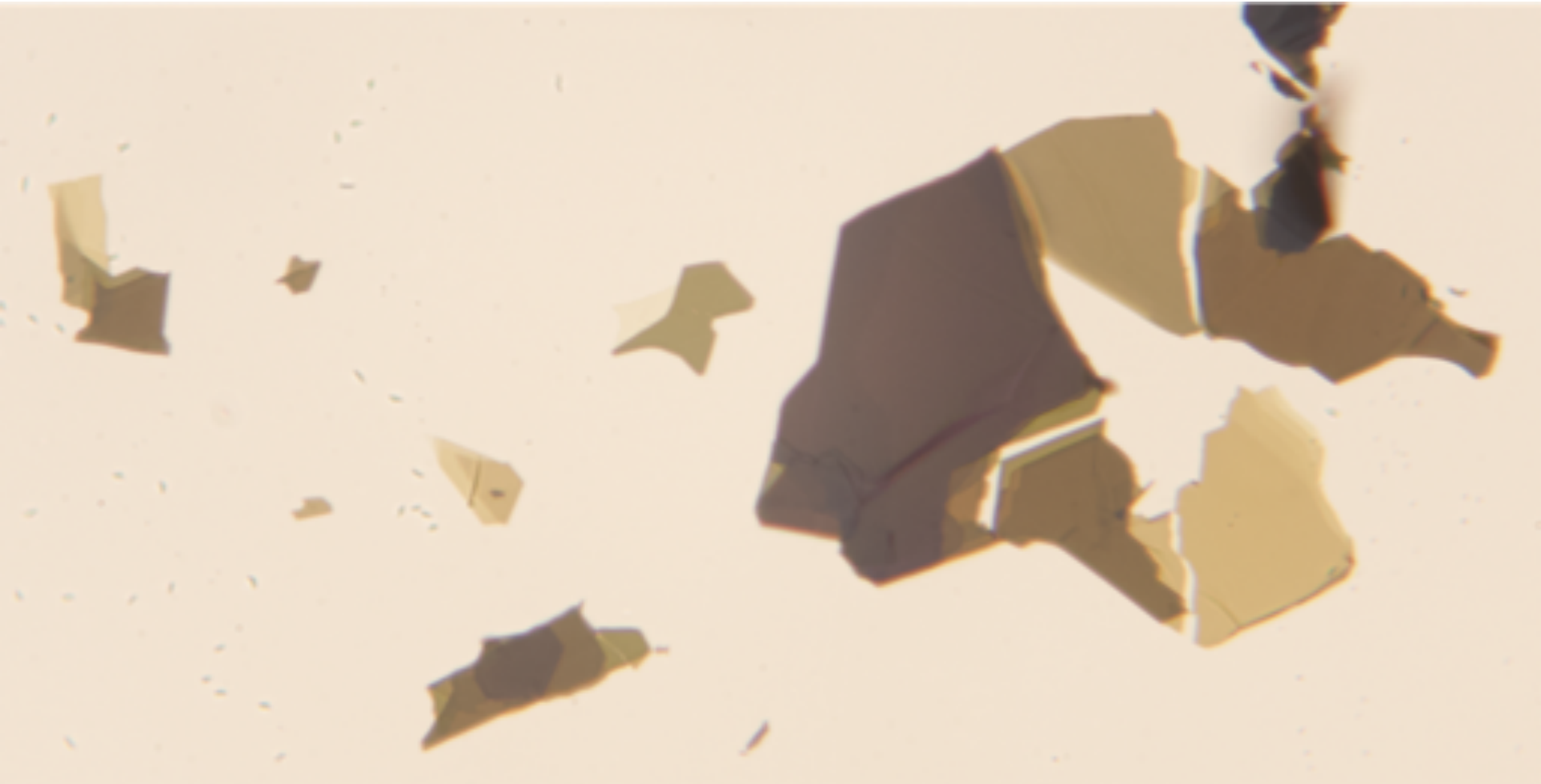


# Preparation techniques

## 3) Mechanical Exfoliation

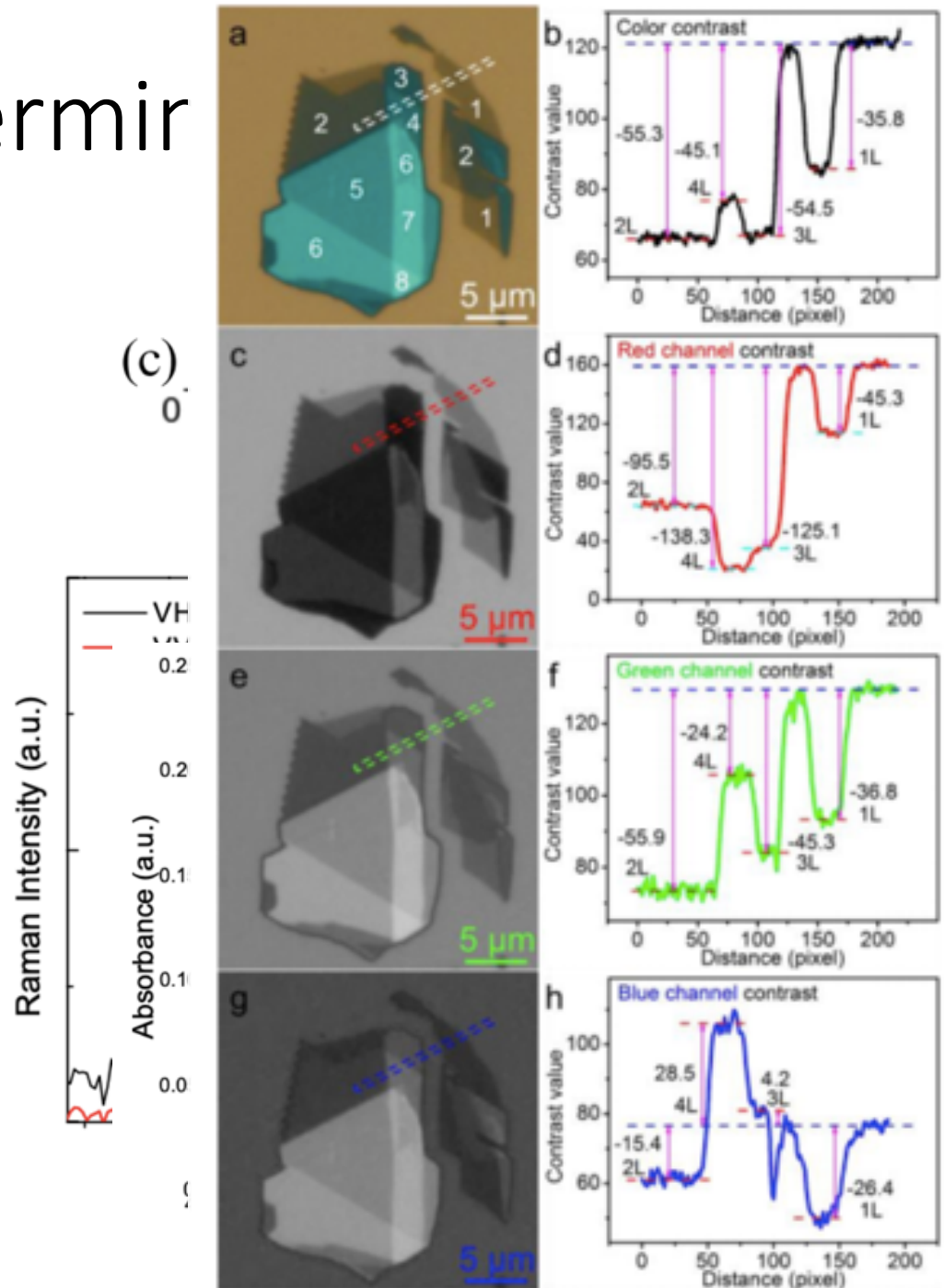


# Thickness determination # layers



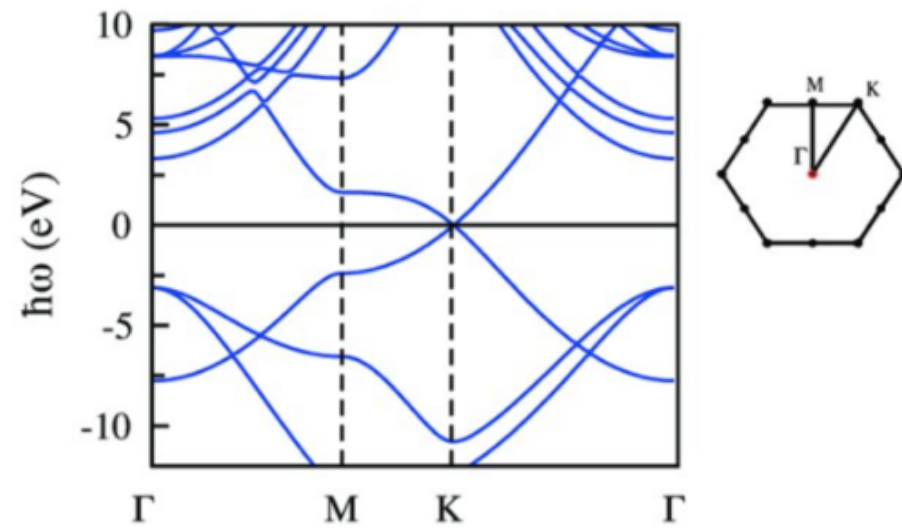
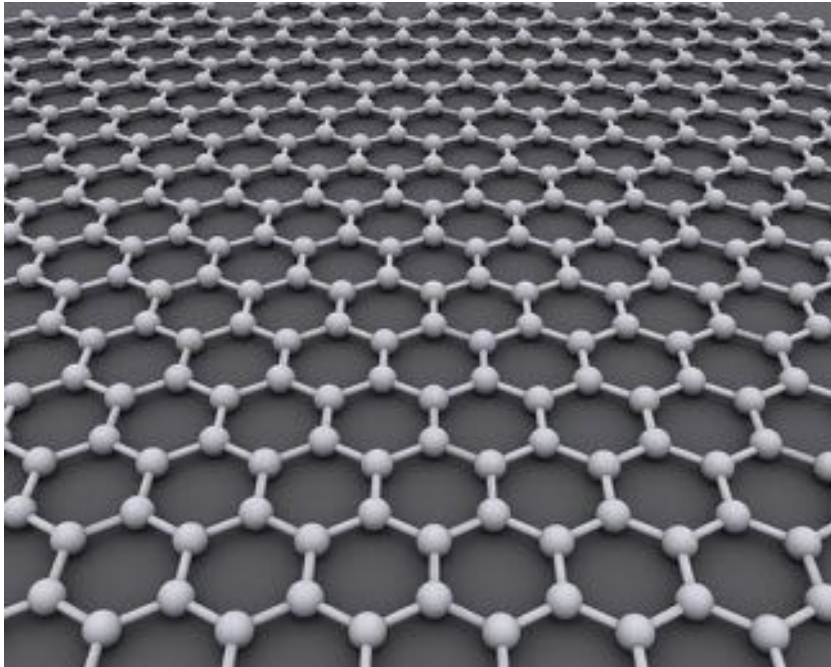
# Thickness determination # layers

- AFM measurements
- Raman Spectroscopy
- Absorbance
- Image analysis

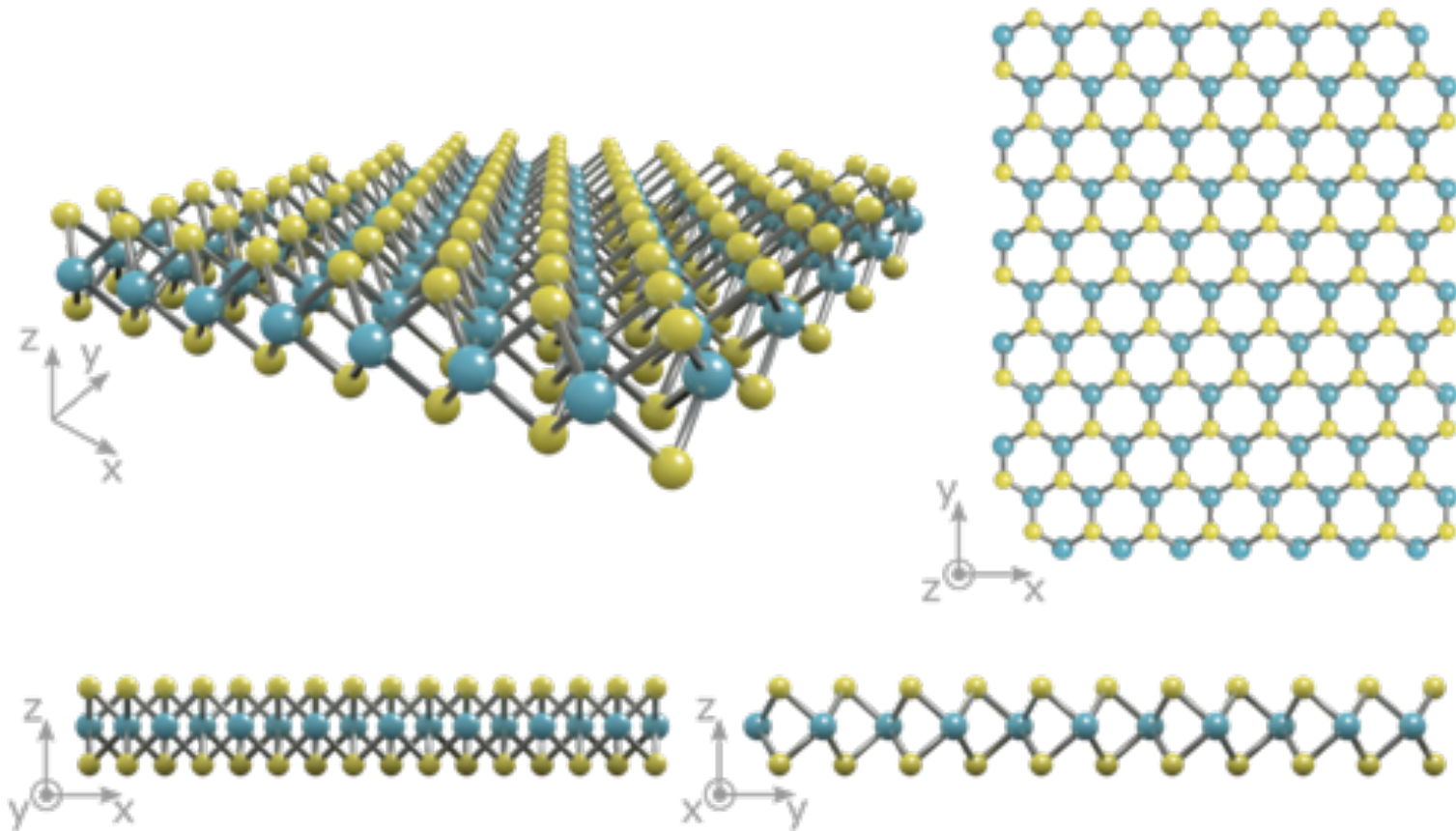




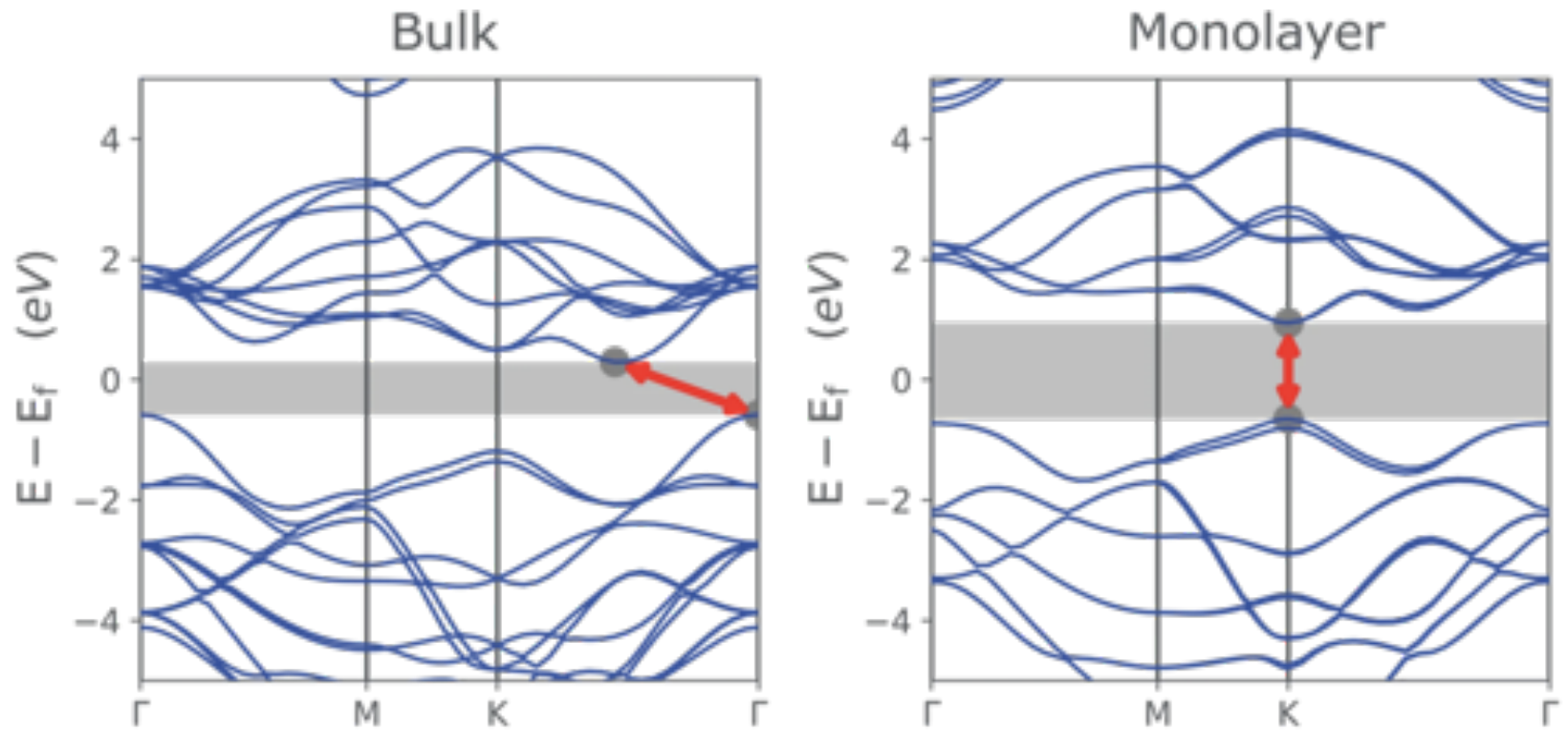
# Graphene



# Molybdenum disulfide - MoS<sub>2</sub>

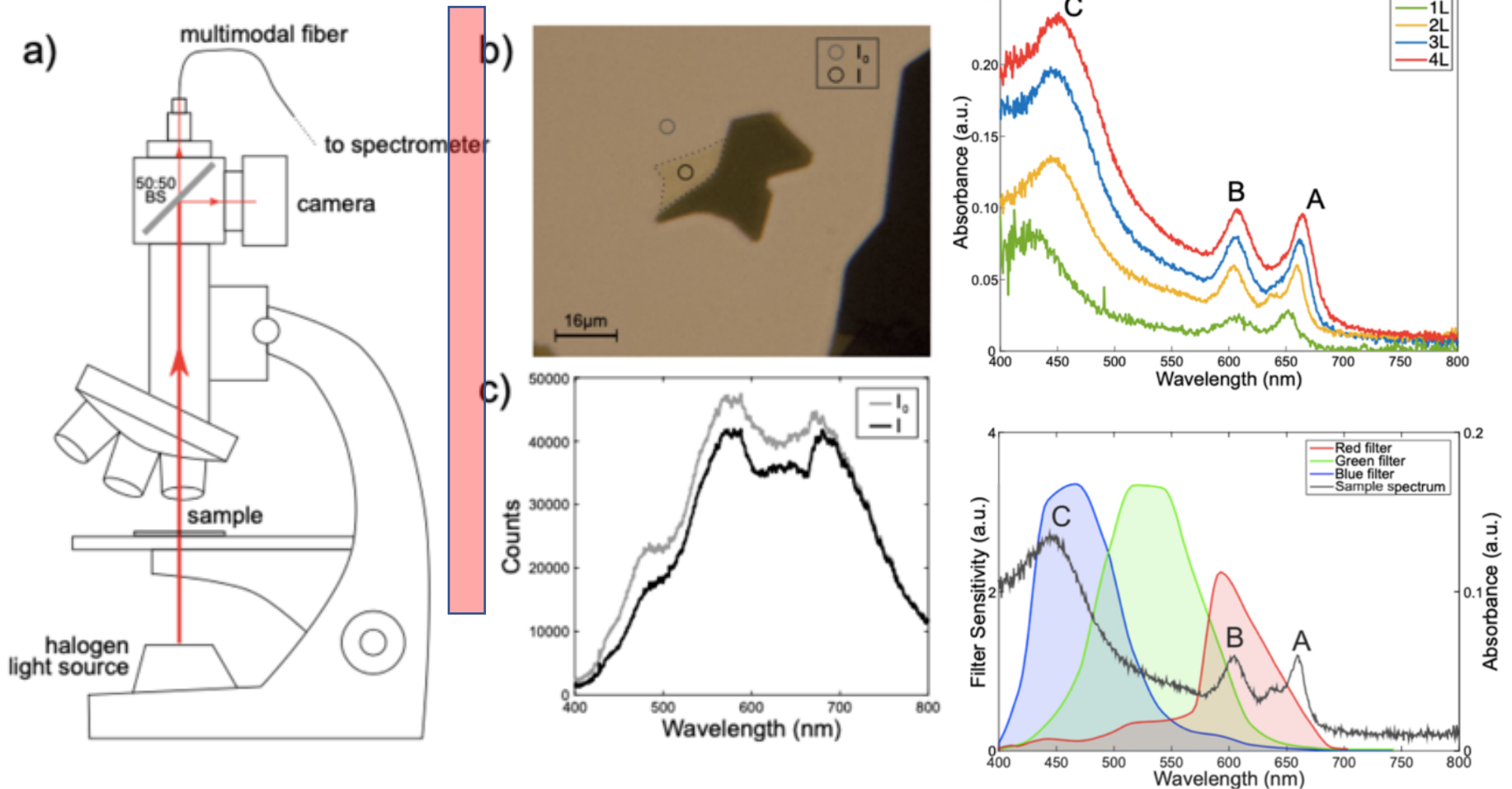


# Molybdenum disulfide - MoS<sub>2</sub>

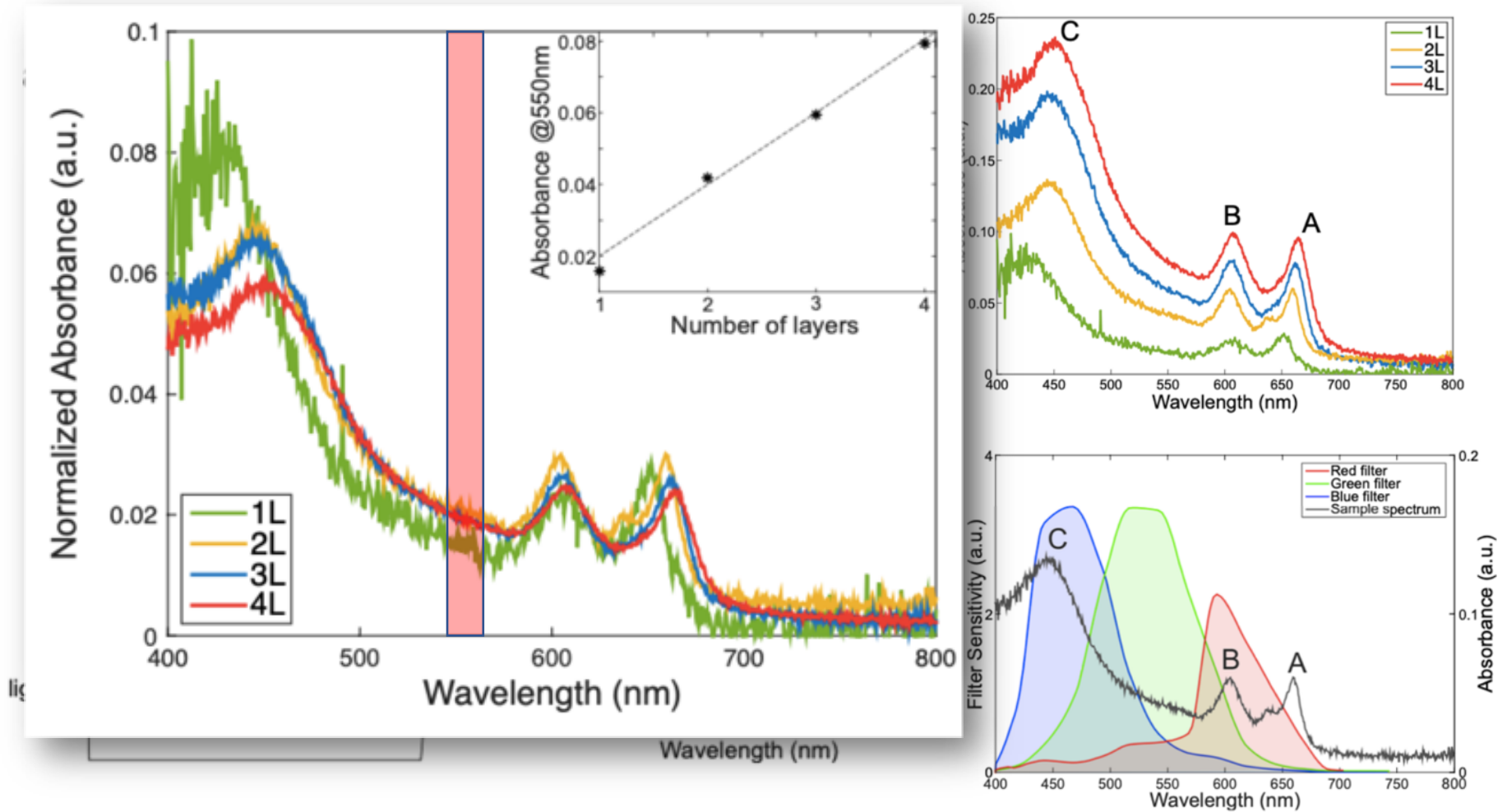


# Fast MoS<sub>2</sub> thickness identification by transmission imaging

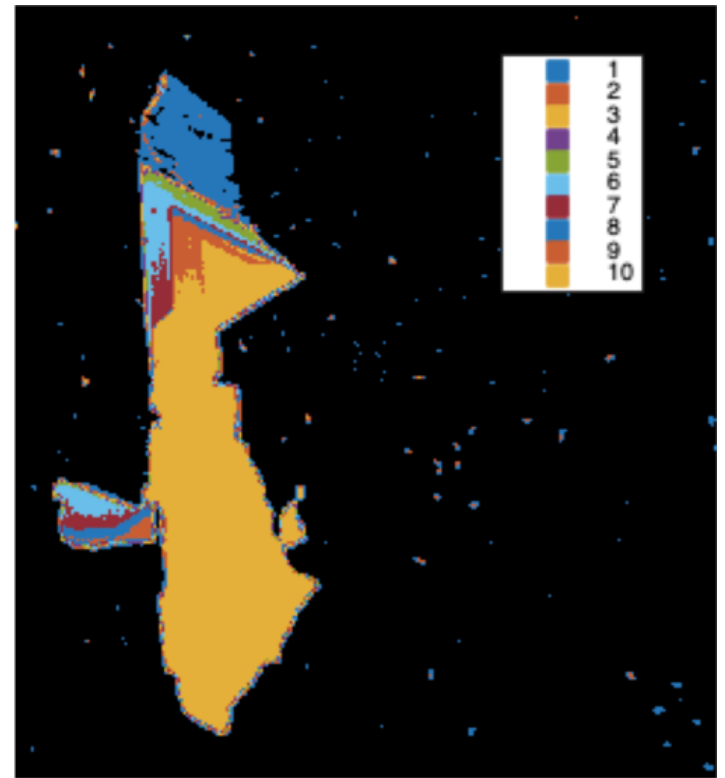
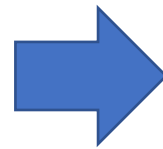
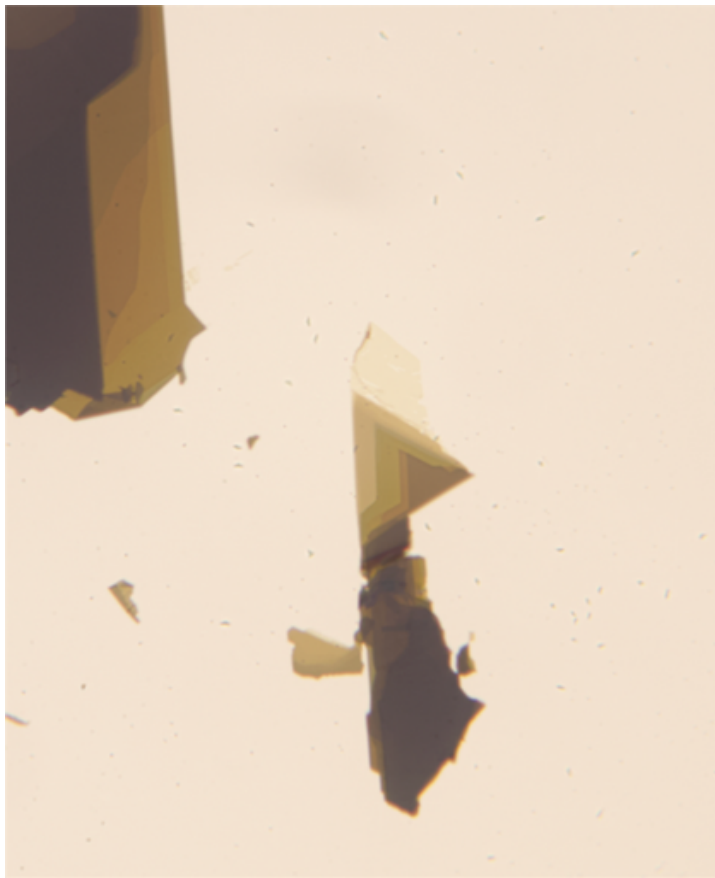
# Fast MoS<sub>2</sub> thickness identification by transmission imaging



# Fast MoS2 thickness identification by transmission imaging

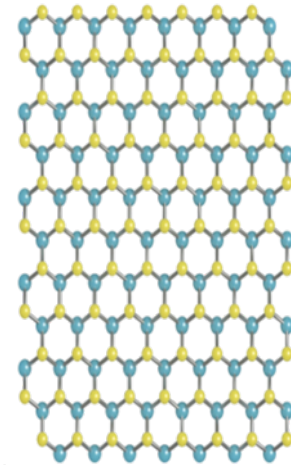
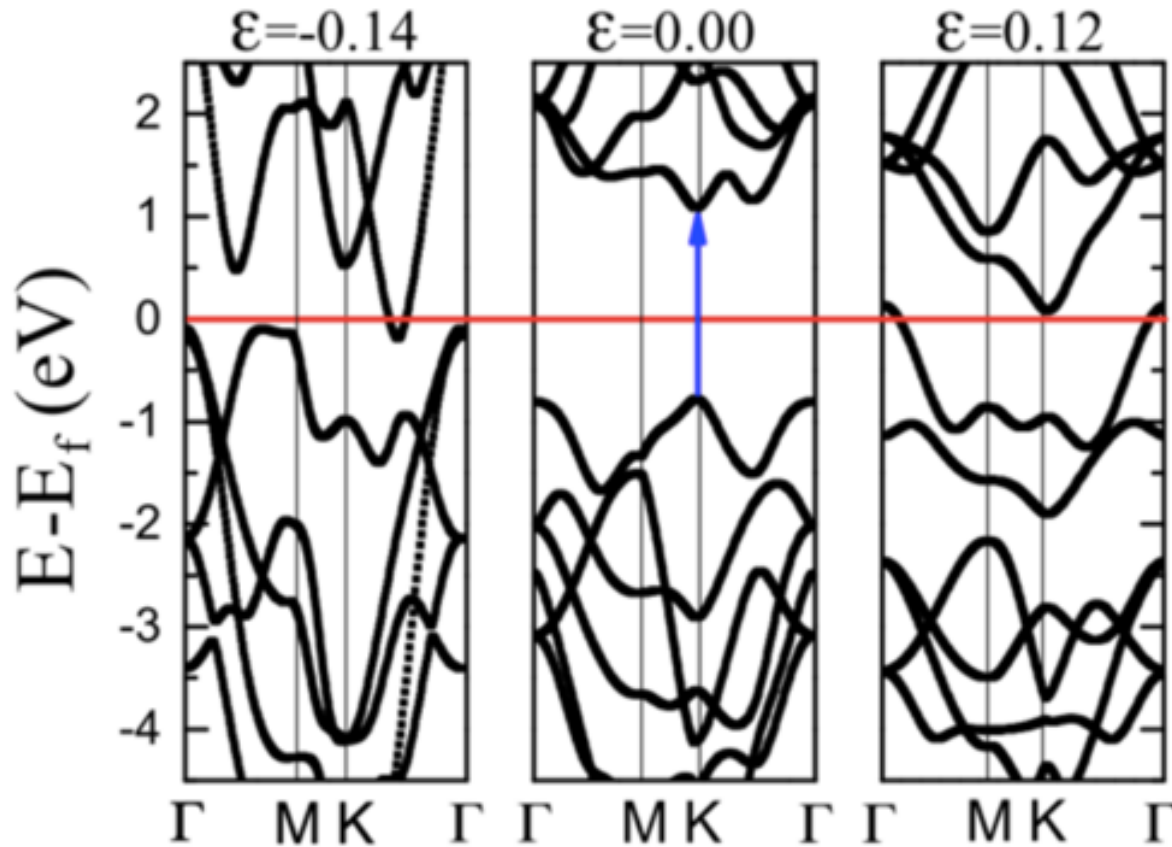
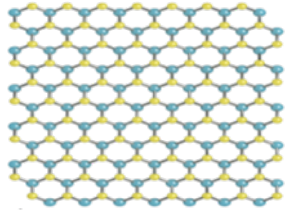


# Fast MoS<sub>2</sub> thickness identification by transmission imaging



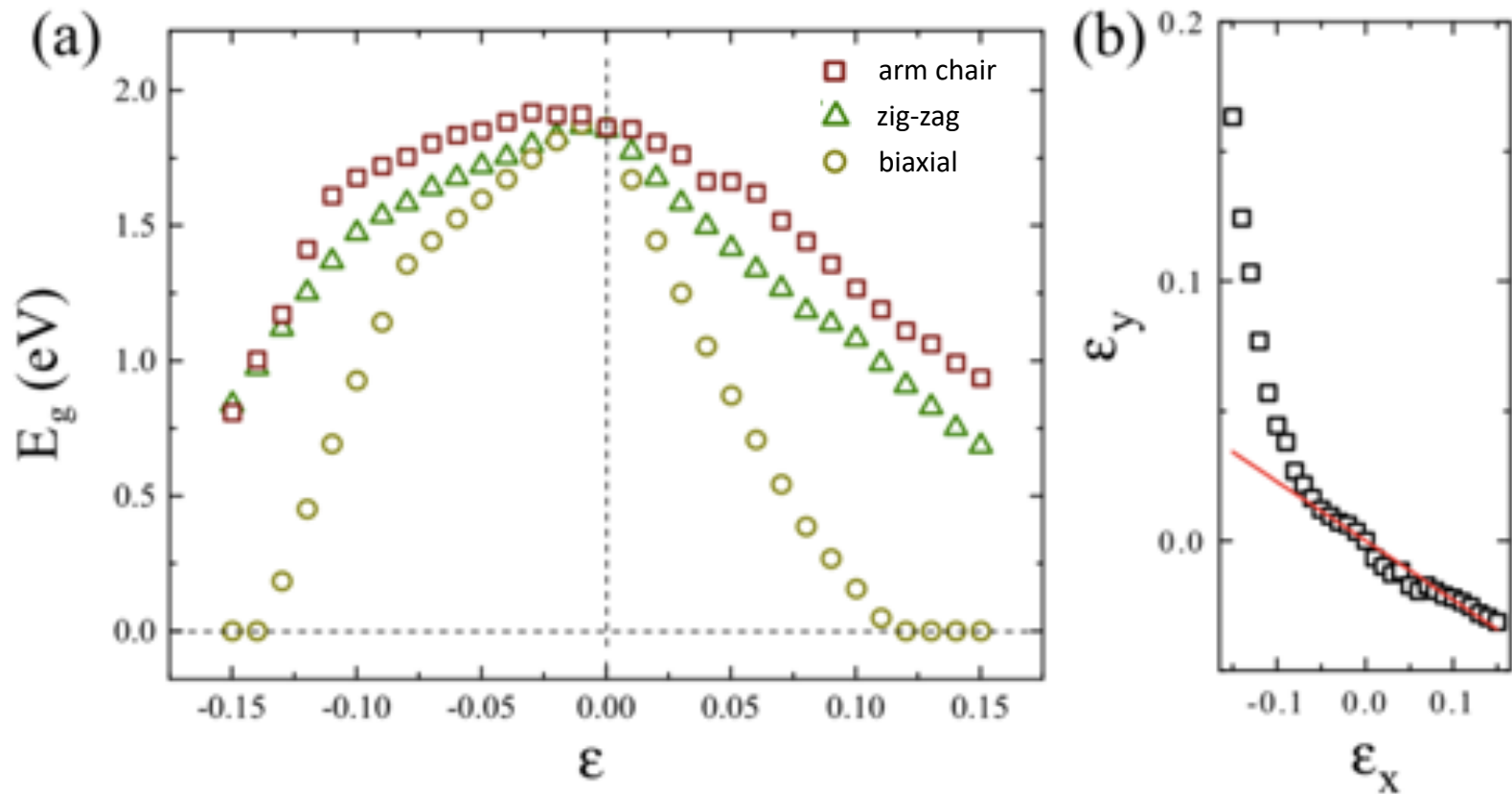


# Molybdenum disulfide - MoS<sub>2</sub>

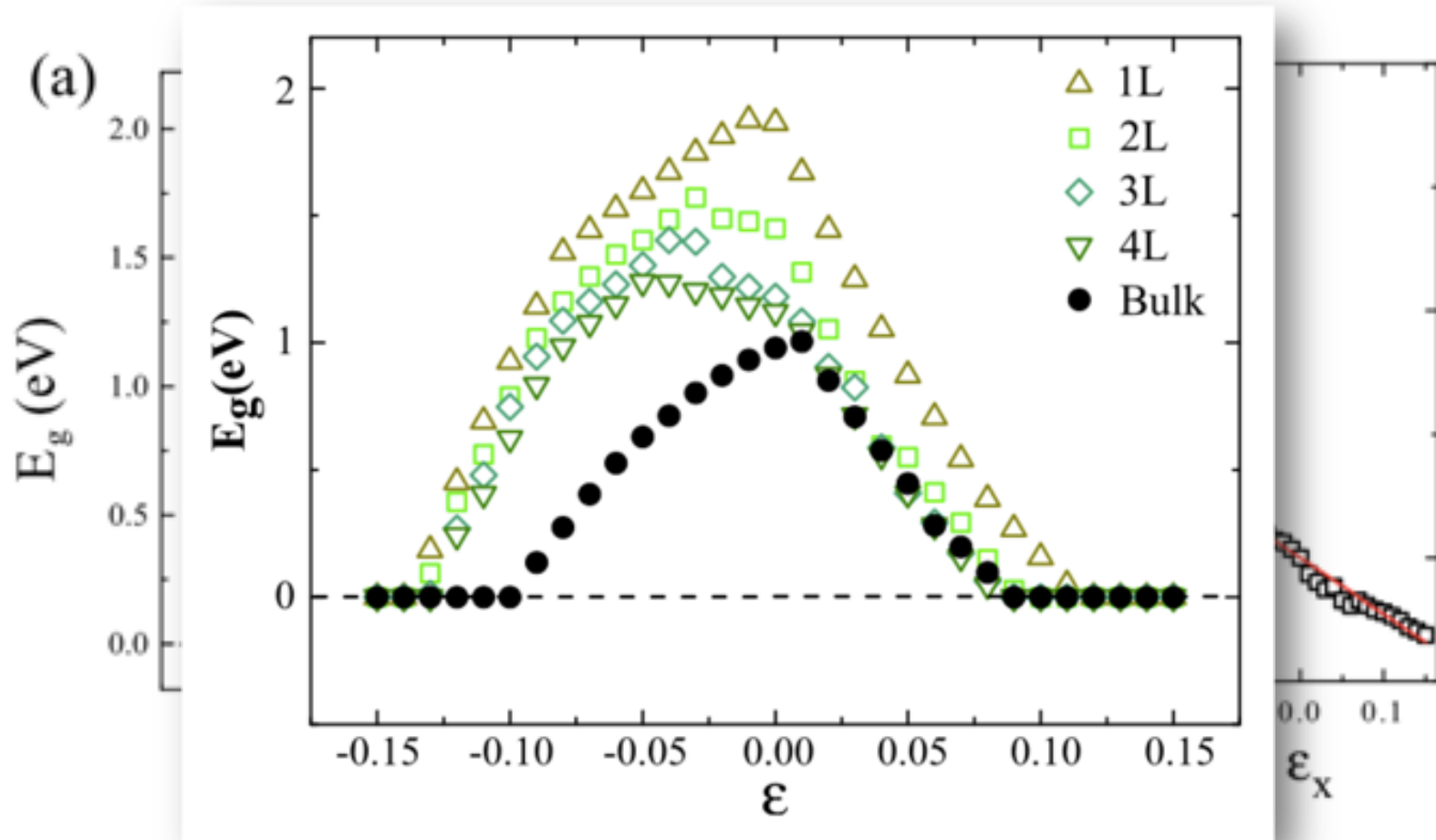




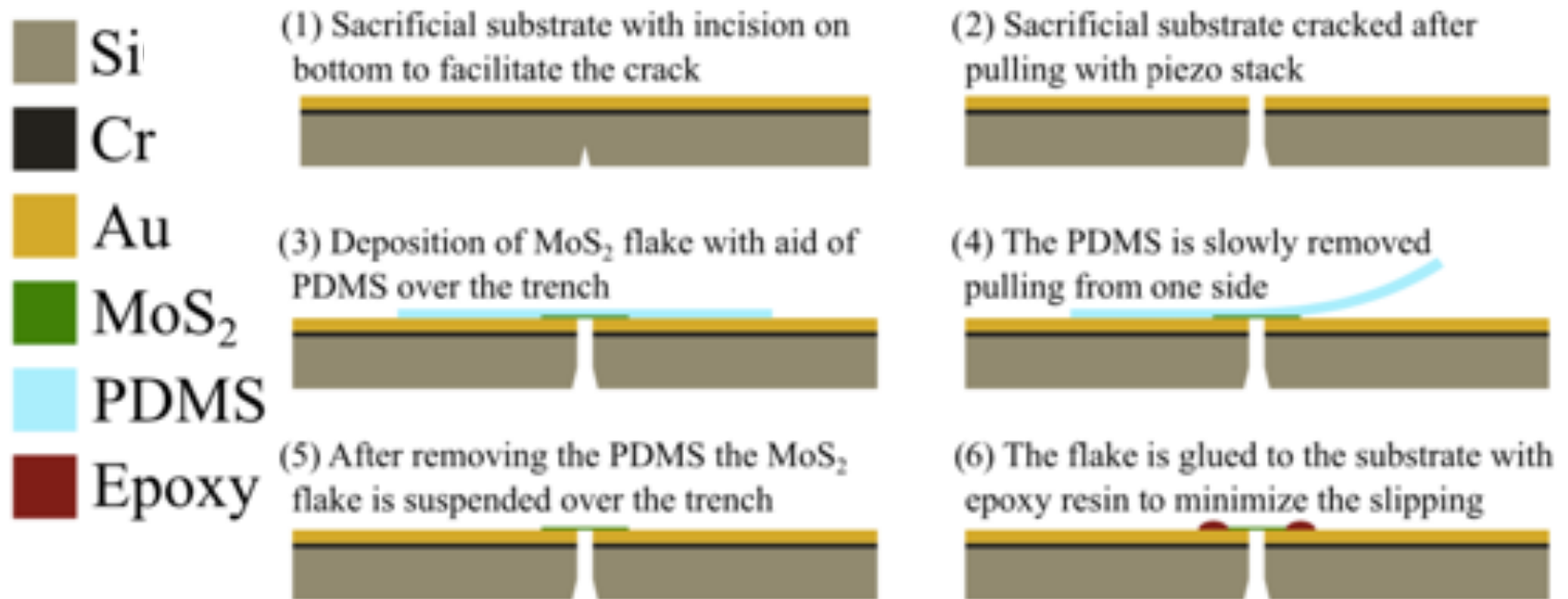
# Molybdenum disulfide - MoS<sub>2</sub>



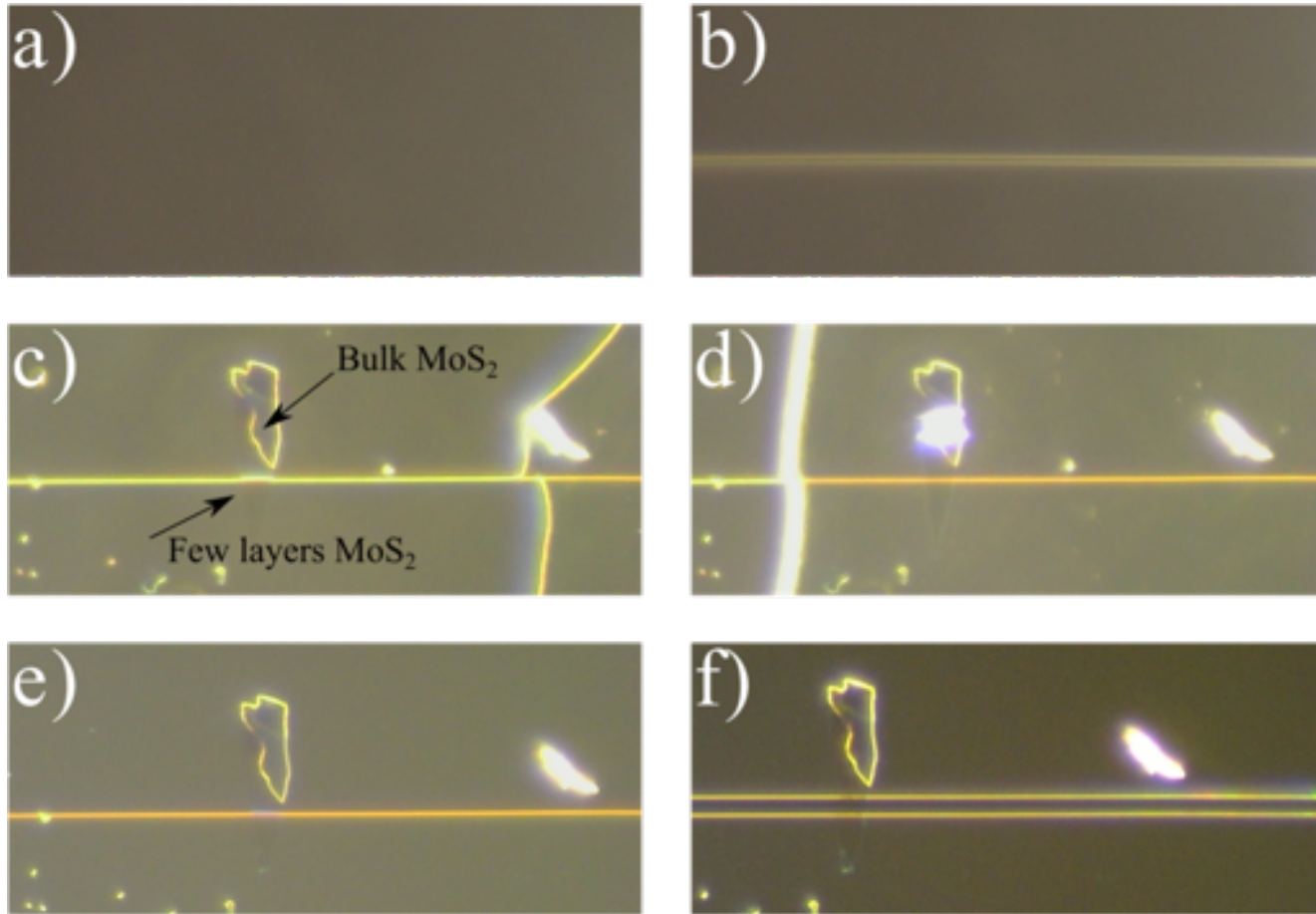
# Molybdenum disulfide - MoS<sub>2</sub>



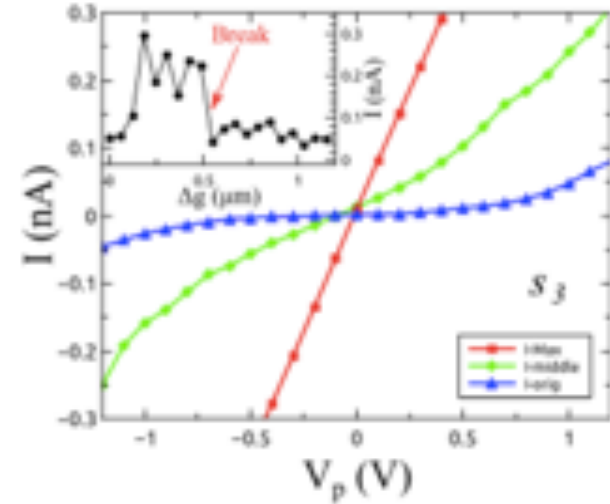
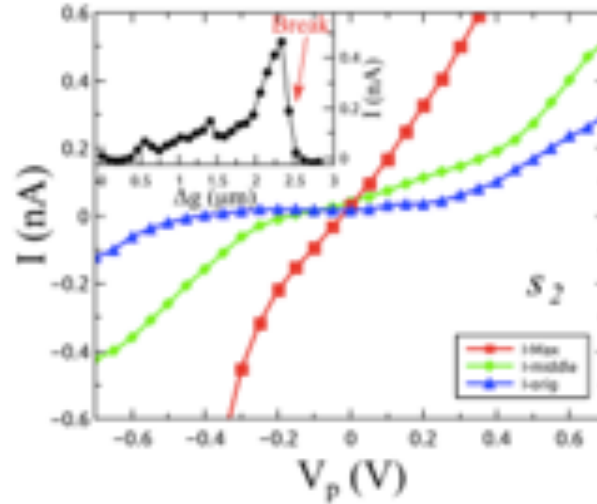
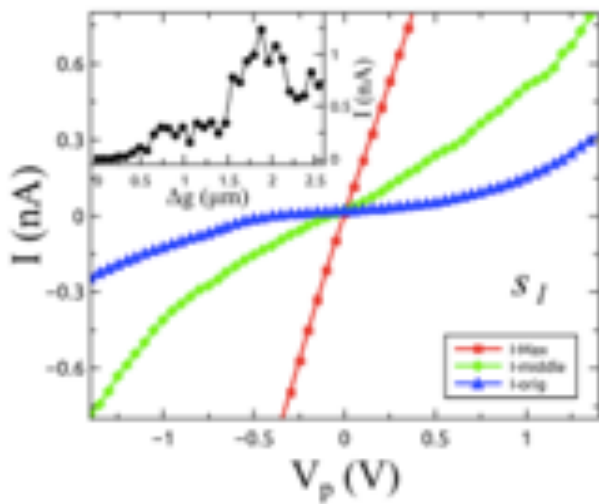
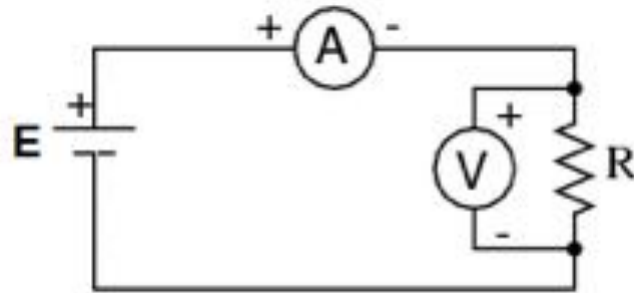
# Electronic transport modulation on few-layer MoS<sub>2</sub> under strain



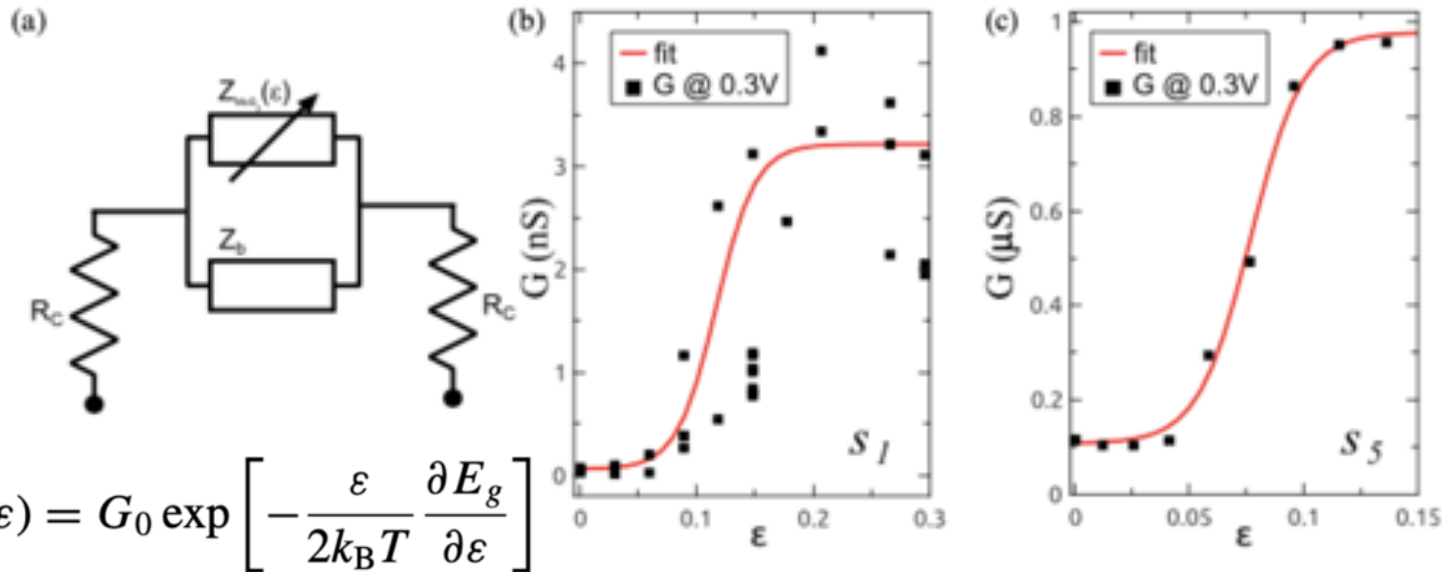
# Electronic transport modulation on few-layer MoS<sub>2</sub> under strain



# Electronic transport modulation on few-layer MoS<sub>2</sub> under strain



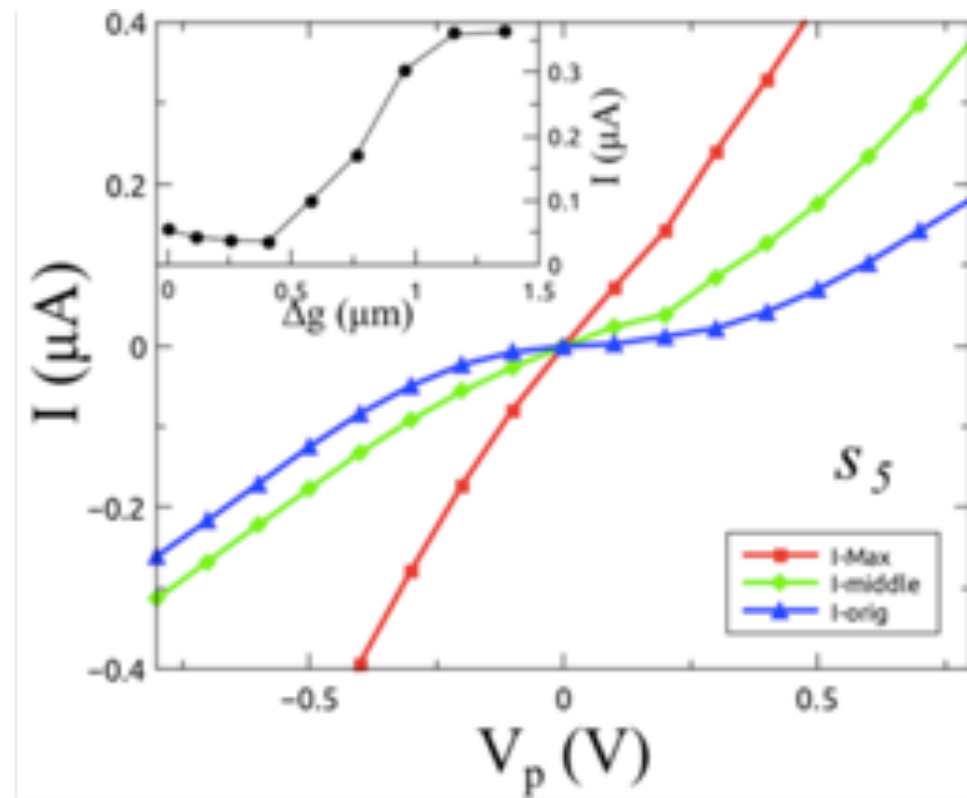
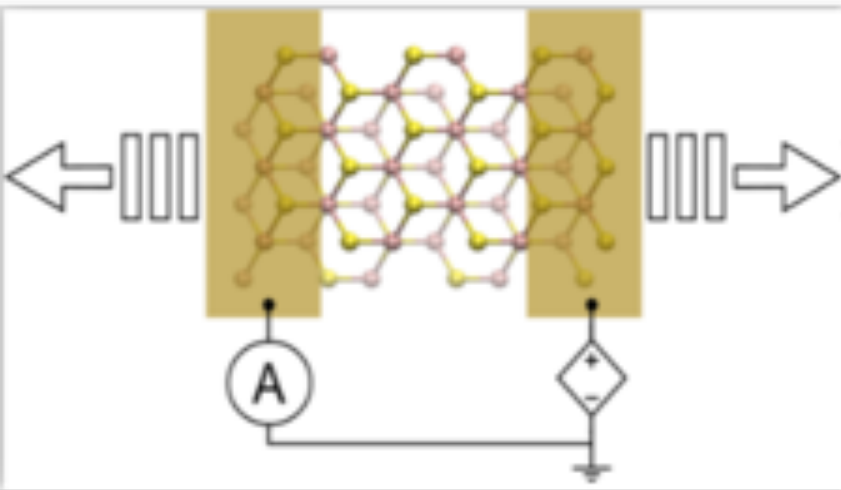
# Electronic transport modulation on few-layer MoS<sub>2</sub> under strain



Parameter	$S_1$	$S_5$
$R_C$	$310.7 \times 10^6 \Omega$	$1.02 \times 10^6 \Omega$
$Z_b$	$1.67 \times 10^{10} \Omega$	$8.24 \times 10^6 \Omega$
$G_0$	$2.94 \times 10^{-12} \text{ S}$	$13.05 \times 10^{-10} \text{ S}$
$\partial E_g / \partial \epsilon$	$-31 \text{ meV}/\% \text{ strain}$	$-45 \text{ meV}/\% \text{ strain}$

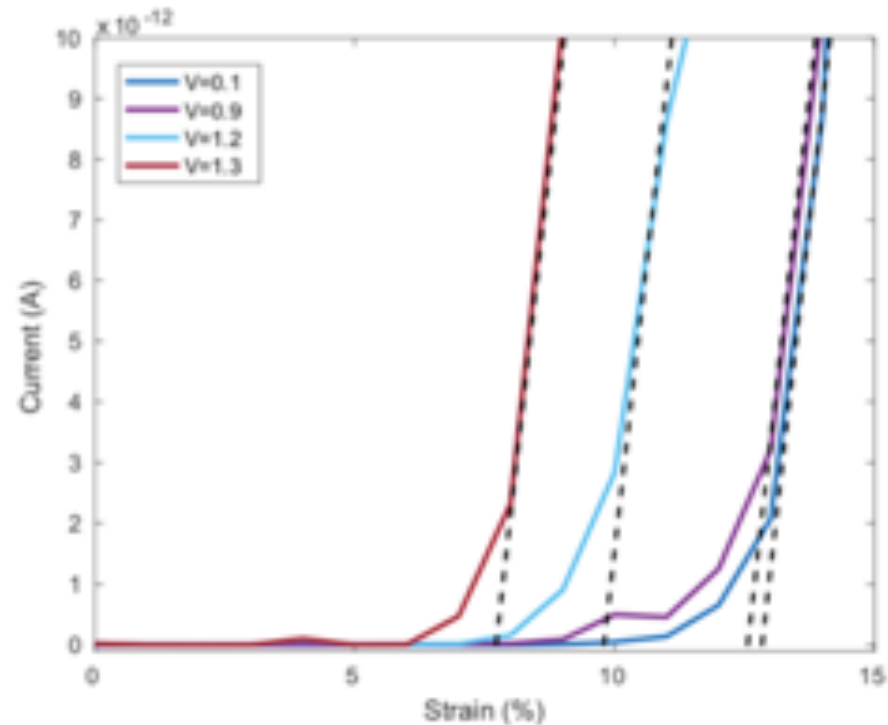
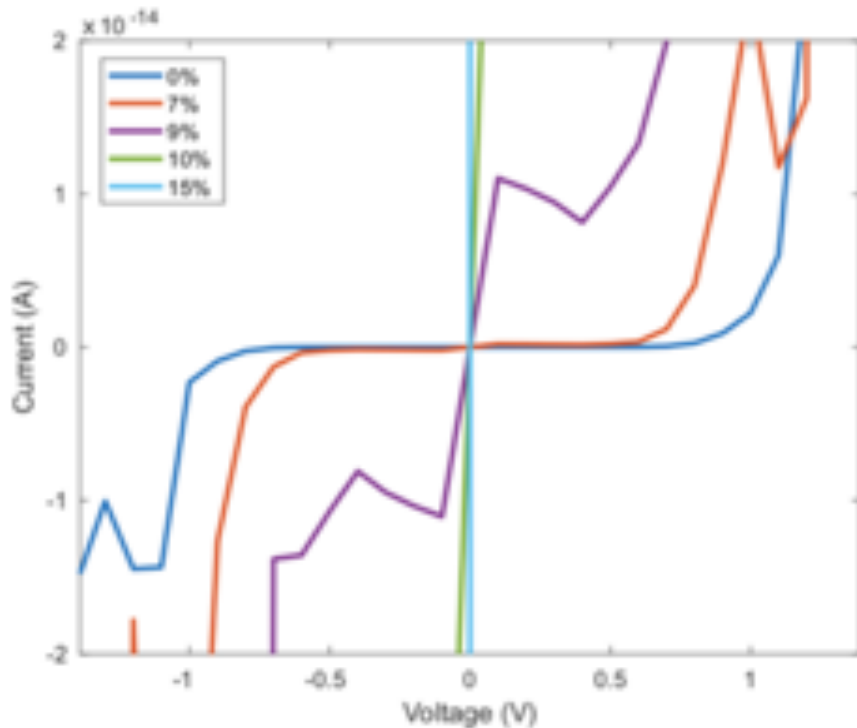
Tunable MoS<sub>2</sub> strain sensor

# Tunable MoS<sub>2</sub> strain sensor



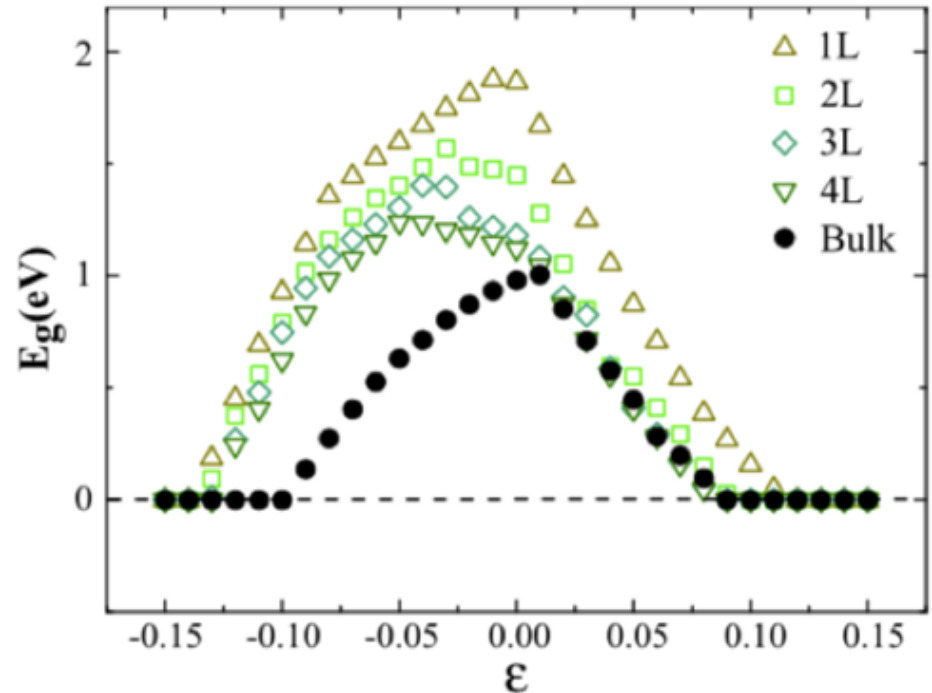


# Tunable MoS<sub>2</sub> strain sensor



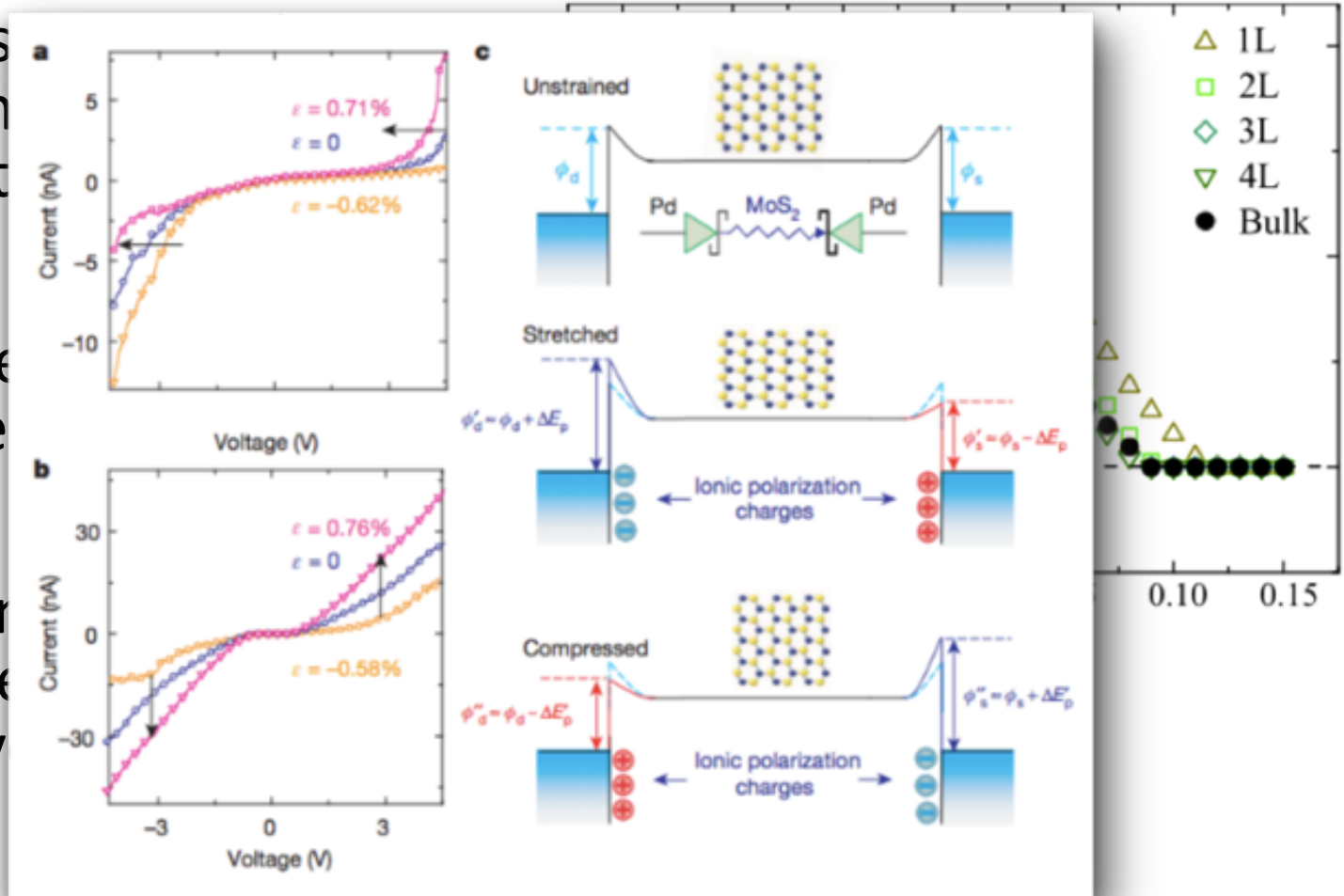
# Tunable MoS<sub>2</sub> strain sensor

- Sensors require direct relation between two properties
- Not direct relation between  $E_g$  and strain
- Solution: exploit piezoelectricity (only odd-layered)



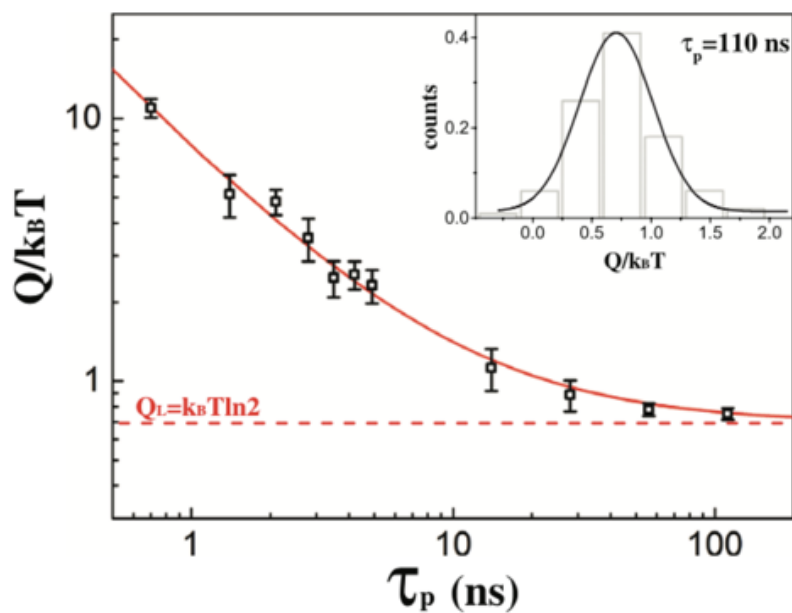
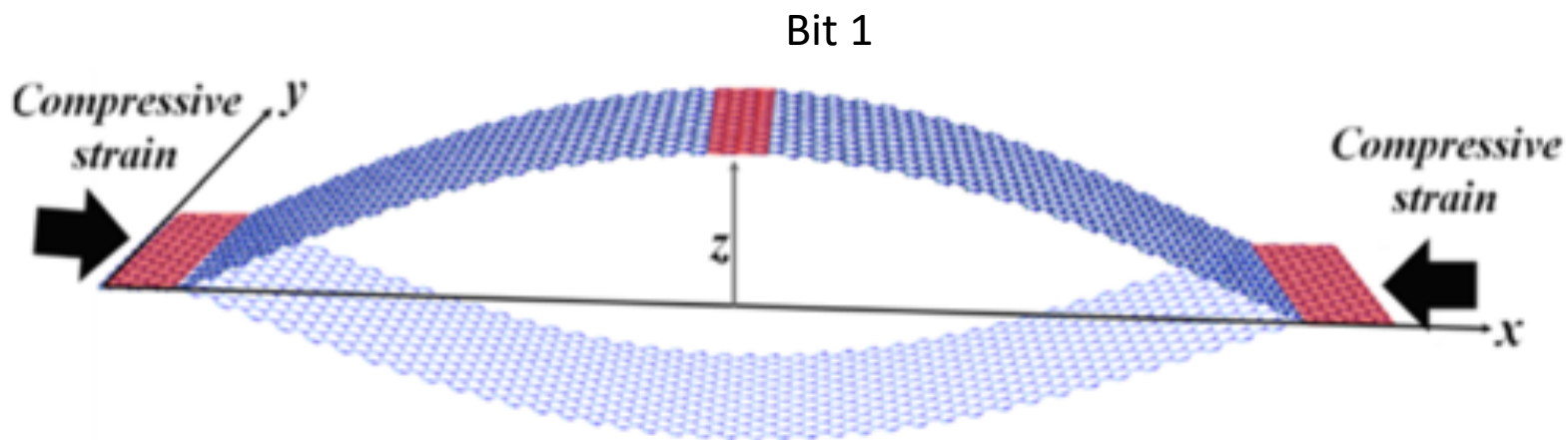
# Tunable MoS<sub>2</sub> strain sensor

- Sensors relation property
- Not directly between
- Solution piezoelectric odd-layer

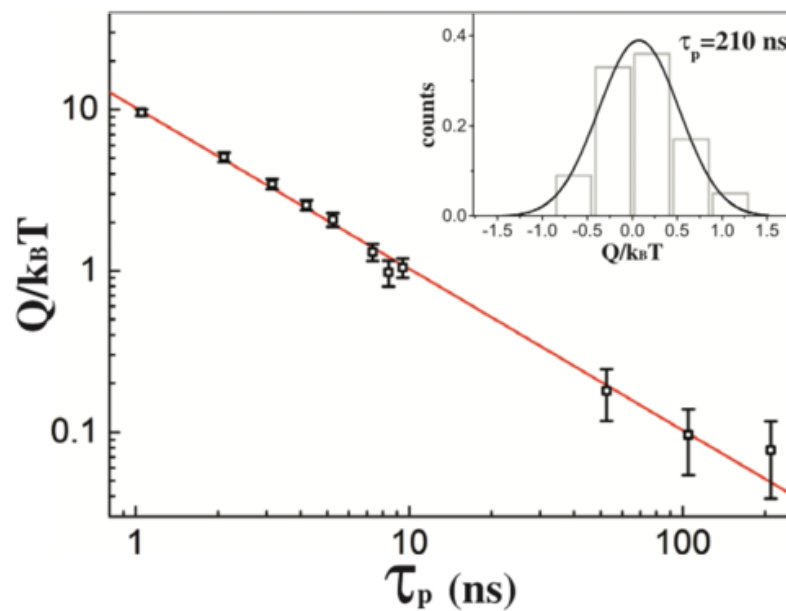


NEMS memory device

# NEMS memory device

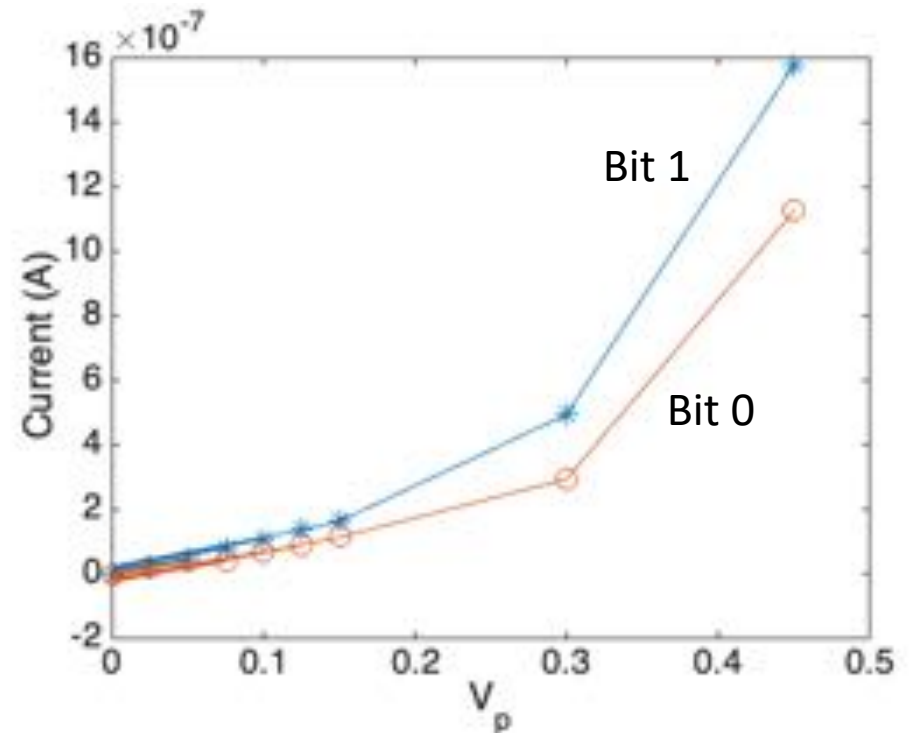
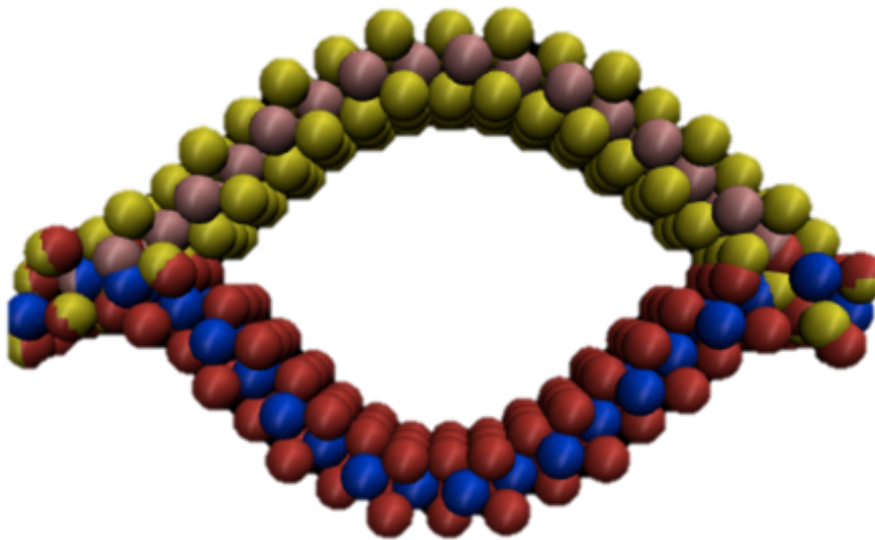


Bit 0



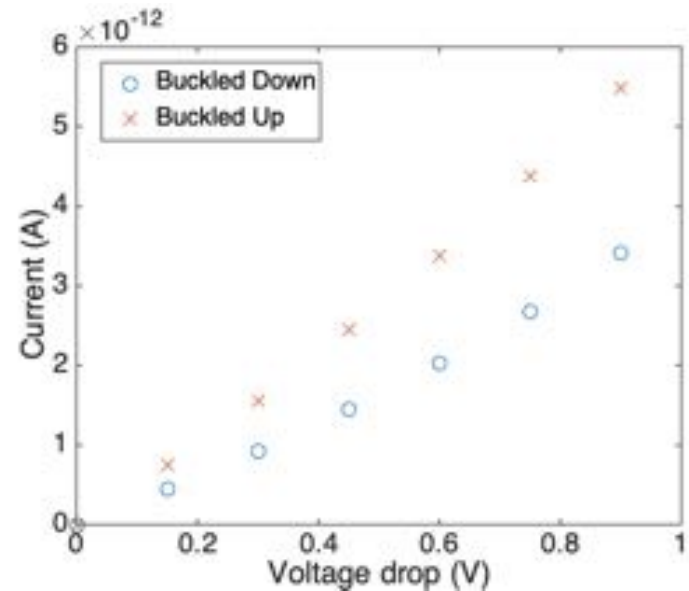
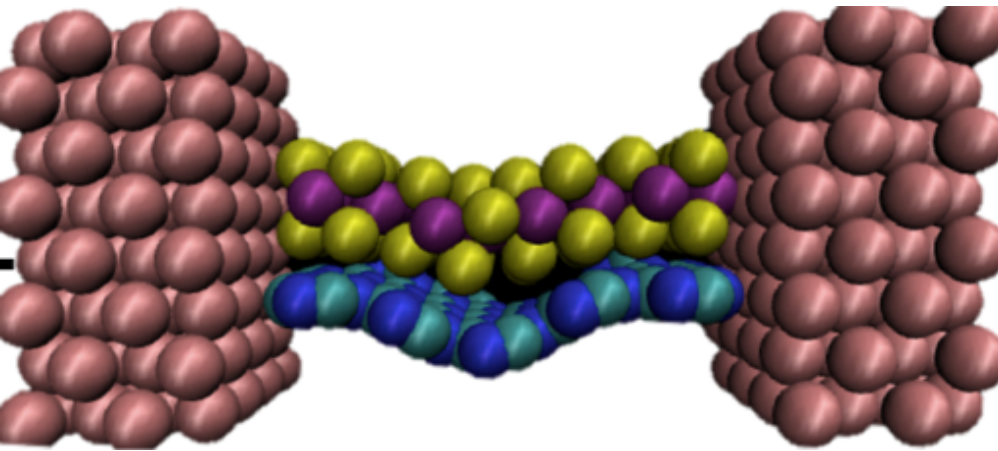
# NEMS memory device

- Asymmetry in the out of plane direction
  - Engineer local strain by asymmetries on clamping



# NEMS memory device

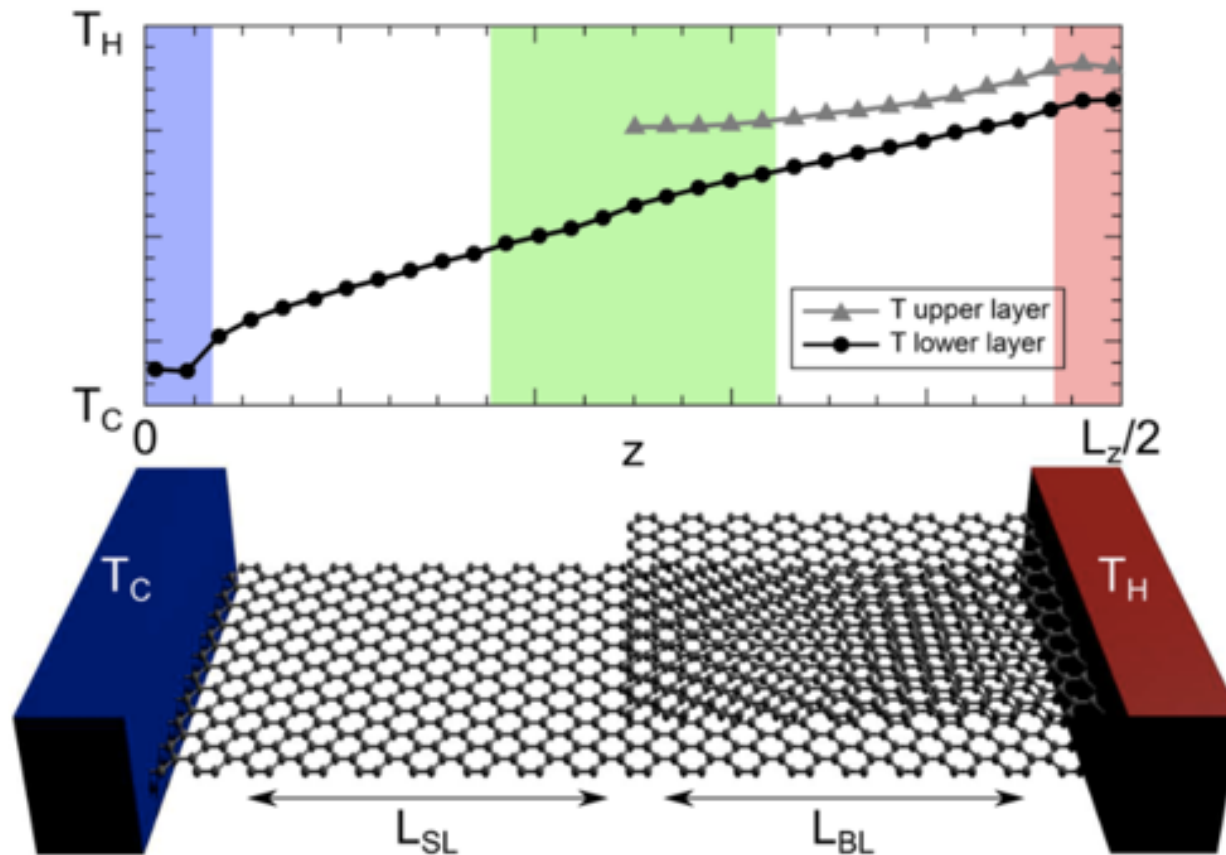
- Heterostructure
  - Piezoresistive and non-piezoresistive materials



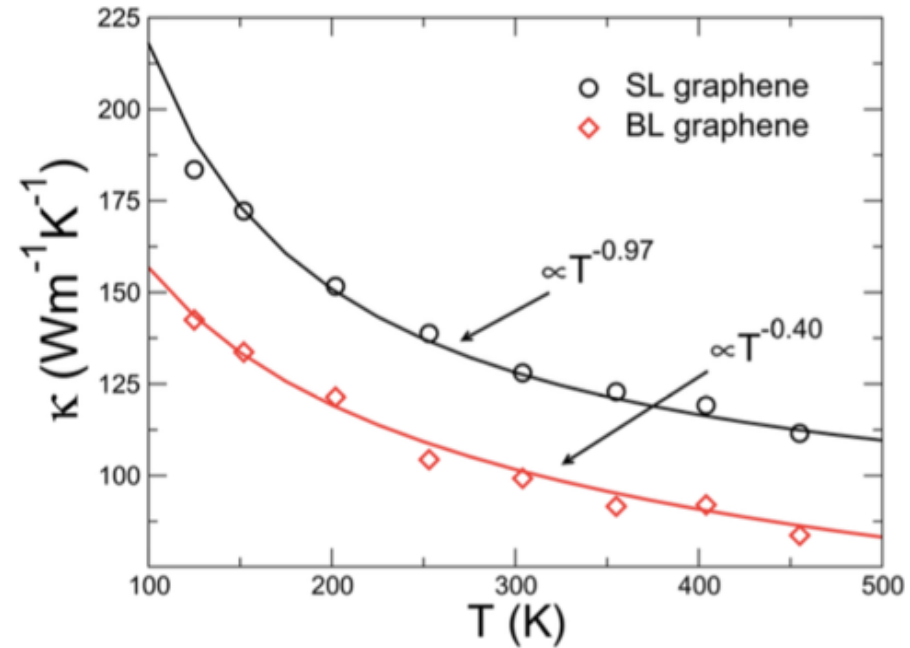
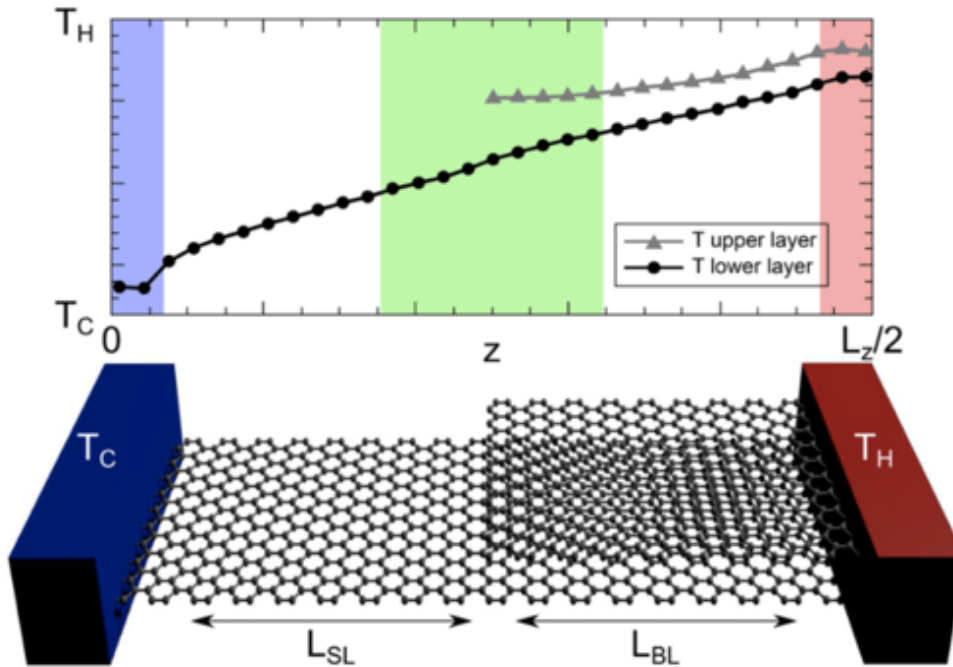
Heat rectifier



# Heat rectifier



# Heat rectifier



Expected  $\gamma_{\max} \sim 5\%$  for  $T=300$  K and  $\Delta T = 100$  K

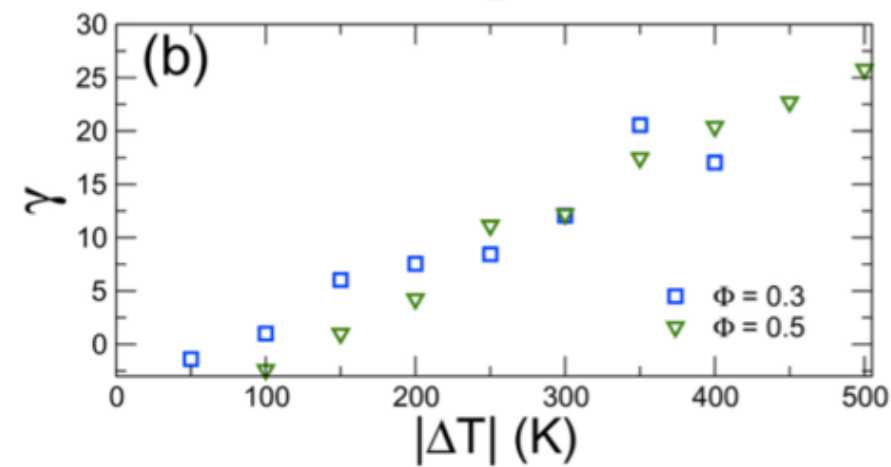
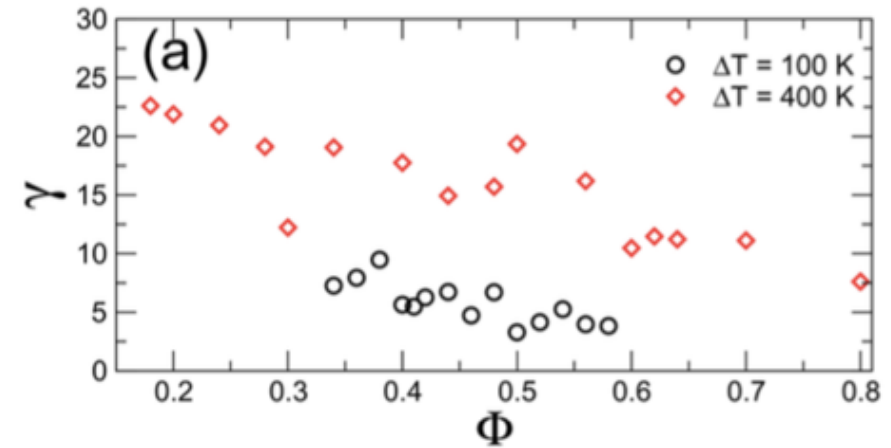
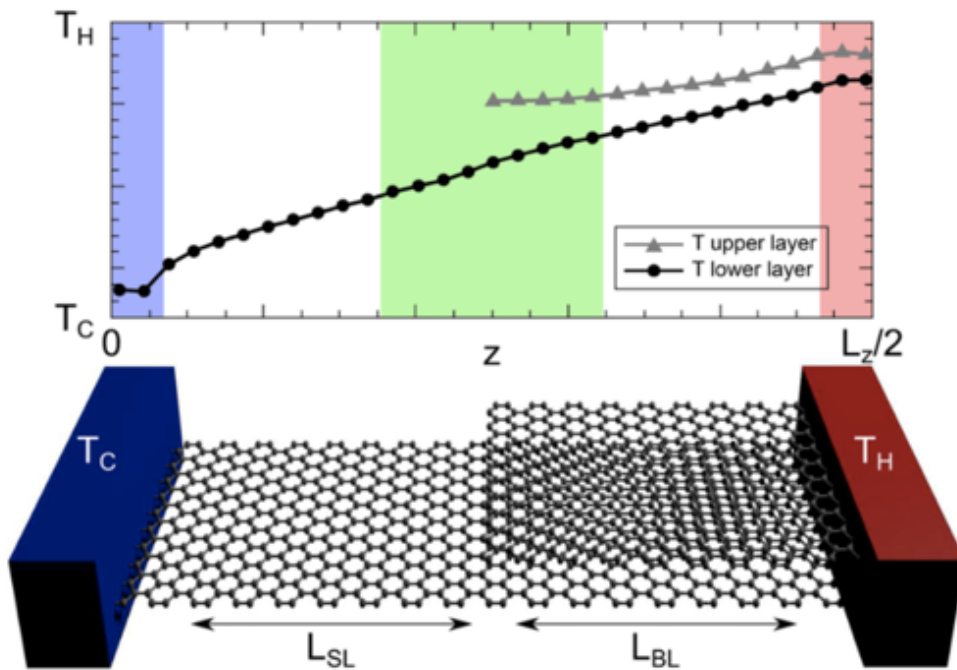
$\gamma_{\max} \sim 20\%$  for  $T=300$  K and  $\Delta T = 400$  K

For bulk

$$\gamma_{\max} \simeq \frac{(n_1 - n_2) \Delta T}{4 T_0}$$

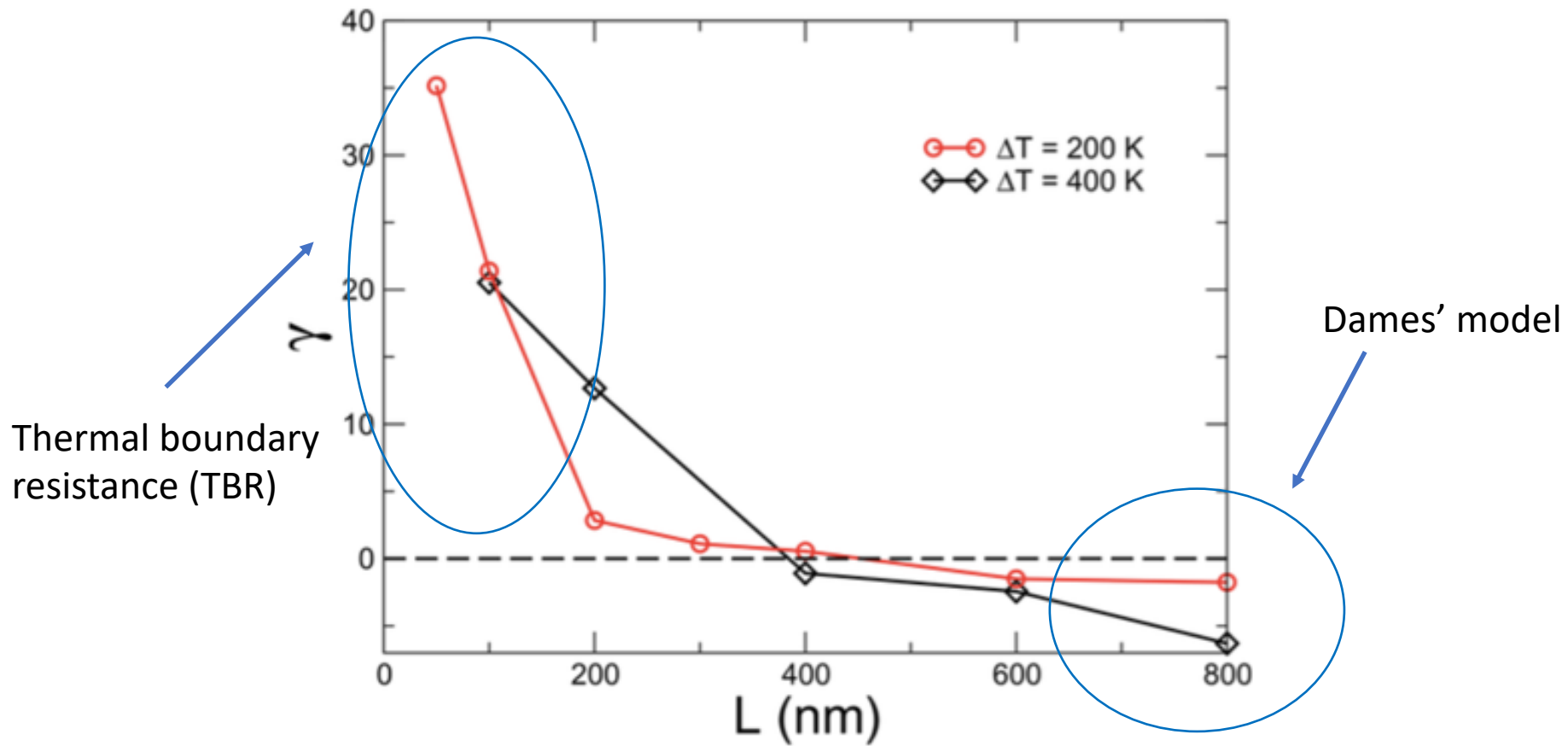
negative

# Heat rectifier



positive

# Heat rectifier



Thank you for your attention

